



U.S.S.N. 10/082,009

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicants: Shih et al.

Group Art Unit: 1746

Serial No.: 10/082,009

Examiner: A. Markoff

Filed: 02/20/2002

In Response to Office Action

Dated: 11/30/2004

For: METHOD FOR PREVENTING CHEMICAL ATTACK ON A COPPER

CONTAINING SEMICONDUCTOR WAFER

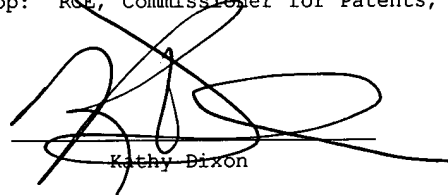
Attorney Docket No.: 67,200-646

Certificate of Mailing

I hereby certify that this paper (along with any referred to as being attached or enclosed) is being deposited with the United States Postal Service on the date shown below with sufficient postage as first class mail in an envelope addressed to: Mail Stop: RSE, Commissioner for Patents, P.O. Box 1450, Alexandria, Va 22313-1450.

Date:

Dec. 17/04



Kathy Dixon

REQUEST FOR RECONSIDERATION
SUPPLEMENTAL AMENDMENT

Commissioner for Patents
P.O. Box 1450
Alexandria, Va 22313-1450

Dear Sir:

In response to an Office Action mailed 11/30/2004,
and telephonic communication of 11/24/2004, please consider the
following remarks.